



Att. Docket No. 10191/1690

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. Serial No. : 09/762,985 Confirmation No. 2674
Title : DEVICE AND METHOD FOR
ETCHING A SUBSTRATE USING
AN INDUCTIVELY COUPLED PLASMA

Applicant(s) : Volker BECKER et al.

Filed : May 8, 2001

TC/A.U. : 1763

Examiner : Luz L. Alejandro Mulero

Docket No. : 10191/1690

Customer No. : 26646

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AMENDMENT AFTER A FINAL OFFICE ACTION

S I R:

In response to the Final Office Action mailed on September 19, 2005 (the three-month response date for which is December 19, 2005 which has been extended by one month to January 19, 2006 by the accompanying petition), please reconsider the above-identified application based on the following:

Amendments to the Claims are reflected in the listing of the claims which begins on page 2 of this paper.

Remarks begin on page 8 of this paper.